

Fig. 1 Schematic diagram of (a) BTO field plated and (b) BTO RESURF trench Ga_2O_3 SBD, (c) Microscope image of the large area (1mm^2) SBD.

Fig. 2 CV and doping profile of the HVPE epitaxial layer from a Pt/ Ga_2O_3 (Bare Schottky) test structure.

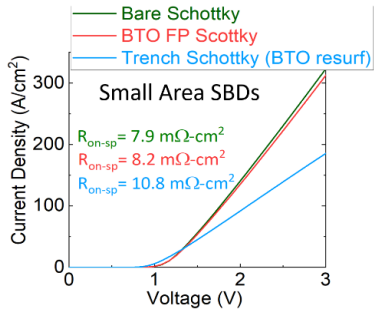


Fig. 3 IV characteristics of three types of SBDs (small area $\sim 200 \times 200 \mu\text{m}^2$)

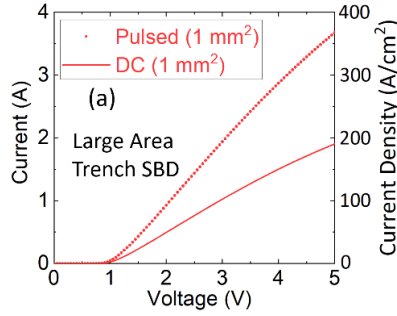


Fig. 4 DC and pulsed IV characteristics of (a) 1mm^2 and (b) 4mm^2 large area SBD.

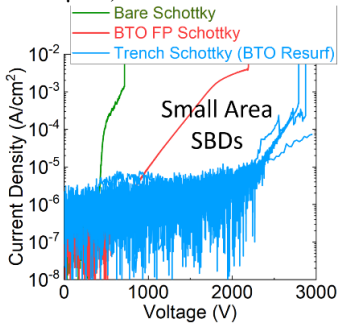
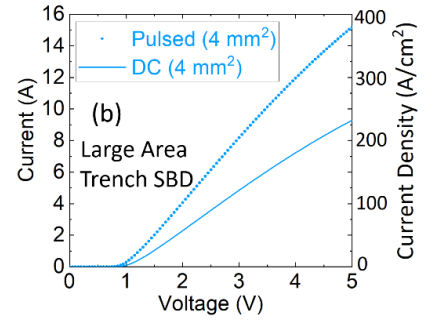


Fig. 5 Reverse IV and breakdown characteristics of the small area SBDs.

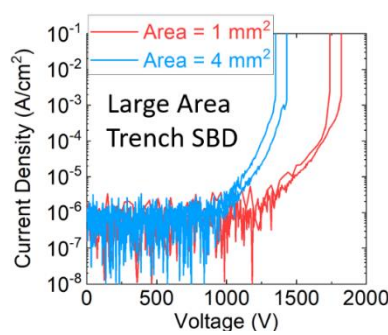


Fig. 6 Reverse IV and breakdown characteristics large area trench SBDs.

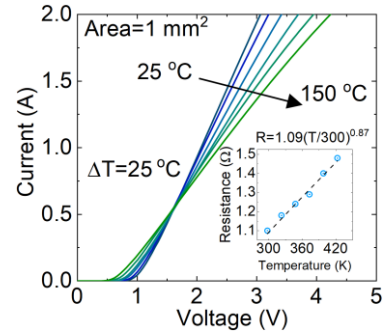


Fig. 7 Temperature Dependent IV Characteristics. The inset shows temperature dependence of the R_{on} and the power law fitting.

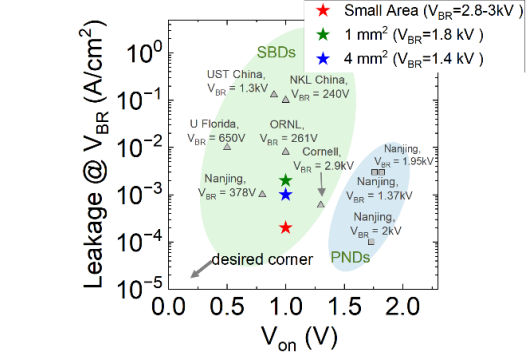


Fig. 8 Benchmark plots showing V_{on} vs I_{Leakage} at breakdown for state-of-the-art $\beta\text{-Ga}_2\text{O}_3$ SBDs

Table I Summary of the performance parameters of high current ($> 1\text{A}$) $\beta\text{-Ga}_2\text{O}_3$ SBDs

Device Type	Area (mm^2)	Current @ ($V_{\text{on}} + 2\text{V}$) (A)	V_{on} (V)	V_{BR} (V)	$R_{\text{on-sp}}$ ($\text{m}\Omega\text{-cm}^2$)	$I_{\text{Leakage}@V_{\text{BR}}}$ (A/cm^2)
Normal SBD (U Florida) JVST. A 39, 013406 (2021).	115	45	0.7	240	-----	-----
FP SBD (Virginia Tech) IEEE Trans. Power Electron. 36, 8565 (2021).	9	20	0.8	700	6.75	-----
NiO JTE SBD (UST China) IEDM. 2022, 210 (2022).	0.78	3	0.9	1300	4.7	0.13
FP JBS (NKL China) IEEE Trans. Power Electron. 36, 6179 (2020).	1	1.7	1	700	7.6	0.005
This Work	1	1 (DC) 2 (Pulsed)	1	~ 1800	~ 10.6	0.001
This Work	4	5 (DC) 9 (Pulsed)	1	~ 1400	~ 10.6	0.002